




IPW

AMENDMENT TRANSMITTAL LETTER			Docket No. 8733.913.00		
Application No. 10/663,805	Filing Date September 17, 2003	Examiner George A. Goudreau	Art Unit 1763		
Applicant(s): Sang-Hyun KIM					
Invention: FABRICATION METHOD OF POLYCRYSTALLINE SILICON TFT.					
TO THE COMMISSIONER FOR PATENTS					
Transmitted herewith is an Amendment and Response to Non-Final Office Action in the above-identified application.					
The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	23	- 23 =	0	x	\$0
Independent Claims	2	- 3 =	0	x	\$0
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					\$0
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity					
<input checked="" type="checkbox"/> No additional fee is required for this Amendment and Response to Non-Final Office Action.					
<input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ _____. A duplicate copy of this sheet is enclosed.					
<input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed.					
<input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached.					
<input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. <u>50-0911</u> as described below. A duplicate copy of this sheet is enclosed.					
<input checked="" type="checkbox"/> Credit any overpayment.					
<input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.					
 Eric J. Nuss Attorney Reg. No.: 40,106				Dated: <u>January 5, 2006</u>	



Docket No. 8733.913.00
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Sang-Hyun KIM

Customer No. 30827

Application No. 10/663,805

Confirmation No. 3765

Filed: September 17, 2003

Art Unit: 1763

For: FABRICATION METHOD OF
POLYCRYSTALLINE SILICON TFT

Examiner: George A. Goudreau

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO NON-FINAL OFFICE ACTION

Sir:

In response to the Office Action dated October 11, 2005, please amend the patent application identified above as follows:

INTRODUCTORY COMMENTS

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.